



# plasma process group

## 16 cm RF Ion Beam Source



### Features

- **RF Discharge (no filament)**
- **Many Available Grid Designs**
- **Variety of Process Gases**
- **Versatile Power Range**
- **Easy Maintenance**

### Applications

- **Sputter Deposition**
- **Etching**
- **Ion Beam-Assisted Deposition**
- **Materials Research**

### Description

Plasma Process Group offers a 16 cm RF ion beam source for larger scale processes. This RF source is ideal for both assist and deposition applications, and is most commonly used in production environments. Using RF discharge (no filaments) minimizes maintenance requirements and allows for a wider range of process gases including many reactive species.

New technology developed by Plasma Process Group has dramatically extended the operating life of RF sources in conductive deposition and etching, making RF a good choice for all types of processes.

*Whether you're in research or production, Plasma Process Group is committed to providing the best support possible. Help is just a phone call away (or email if you prefer). Our people have many years of experience with ion beam sources, systems, and applications, and we're happy to share that with you. Give us a call.*

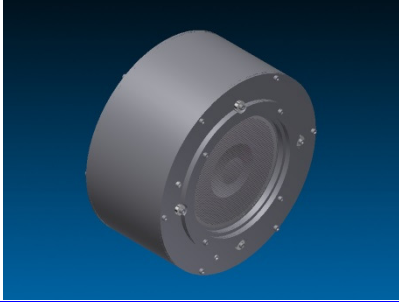
Molybdenum, Titanium, and Pyrolytic Graphite grids are available for this ion source. The 16 cm ion source is typically flange-mounted, but internal mounting is available. Grid assemblies can be custom designed to shape the beam for your specific substrate and vacuum chamber. A new high-current configuration is available, offering up to 800mA with the I-Beam 703 Power Supply, or up to 1A with a separate RF generator.

We understand that every ion beam installation is unique and we're ready to meet the requirements of your specific application.

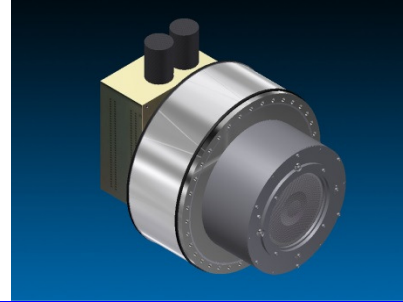
## Specifications

## 16 cm Source

Internal Mount

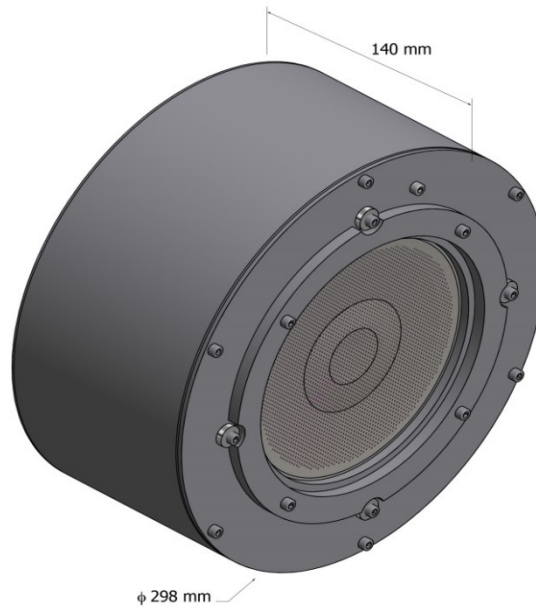


Flange Mount (16.5" CF)



Ion source	16 cm RF
Model number	16RF08
Beam size at grids	16 cm
Beam current	100-1000 mA
Beam energy	100-1500 eV
Grid material	Molybdenum, Titanium, or Pyrolytic Graphite
Beam neutralization	RF Neutralizer (sold separately)
Cooling	Water-Cooled Antenna and Shroud
Power supply	I-BEAM™ 703
Weight	7.7 Kg (17 lbs.)

## Dimensions



**Ordering Information:** 16 cm ion beam sources are available with options such as internal and flange mount kits to facilitate installation. A variety of grid designs are available for your output ion beam. Please contact us to configure your ion beam source.

### Suggested Accessories:

IBEAM 703

I-BEAM™ 703 RFS/RFN Power Supply w/ built-in 500W RF Generator

504424B

RF Neutralizer

504552A/504553A

ATN-10 Matching Network for source / PT-II Auto Controller for Matching Network



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